


<b>PTO-1449</b>  <b>Information Disclosure Citation in an Application</b>		Application No.		Applicant(s)			
		Unassigned		Pascal Huyghe et al.			
		Docket Number		Group Art Unit	Filing Date		
		064441.0263		Unknown June 27, 2003			
<b>U.S. PATENT DOCUMENTS</b>							
		DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
	A.						
	B.						
	C.						
	D.						
	E.						
	F.						
	G.						
	H.						
	I.						
	J.						
	K.						
<b>FOREIGN PATENT DOCUMENTS</b>							
		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO
	L.						
	M.						
	N.						
	O.						
	P.						
	Q.						
<b>NON-PATENT DOCUMENTS</b>							
		DOCUMENT (Including Author, Title, Source, and Pertinent Pages)					DATE
MA	R.	Edward Suttle et al.'s "Streamlining the front-end reticle fabrication process by improving mask ordering" at internet address < <a href="http://www.micromagazine.com/archive/02/06/suttle.html">http://www.micromagazine.com/archive/02/06/suttle.html</a> > and published in June 2002 Issue of Micro Magazine. 10 Pages					June 2002
MA	S.	Brock Hotaling, "MaskPilot Revolutionizes Semiconductor Software," <u>Reticle and Mask Solutions</u> , Vol. 1, No. 1, Fall 2002, 4 Pages					Fall 2002
	T.	Photonics, Inc., "Photonics eBeam Phase Masks: Tackling the Challenges of Special Lightwave Applications," <u>Reticle and Mask Solutions</u> , Vol. XIII, No. 1, Spring 2002, 4 Pages					Spring 2002
EXAMINER					DATE CONSIDERED		
					2/24/2006		
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.							